

wherein a convex body or a convex portion is formed on the surface of said ceramic substrate.

13. (Amended) The ceramic heater according to claim 1,
wherein an electrostatic electrode is set up inside said ceramic substrate.

IN THE ABSTRACT

Please amend the Abstract as follows:

ABSTRACT

04201-2109250
A ceramic heater which makes it possible to make the distance between a semiconductor wafer and the heating surface of a ceramic substrate constant at any time, heat the semiconductor wafer at an even temperature, and prevent contamination of the semiconductor wafer, and which does not cause dropping-out of a supporting pin. The ceramic heater includes a ceramic substrate on a surface of which or inside which a heating element is formed, wherein the ceramic heater is constituted to have a structure such that an object to be heated can be held apart from a surface of the ceramic substrate and heated.

REMARKS


Favorable consideration of this application, as presently amended, is respectfully requested.

The present Preliminary Amendment is submitted to place the above-identified application in more proper format under United States practice. By the present Preliminary Amendment the claims have been amended to no longer recite any multiple dependencies. The Abstract has also been amended to be in more proper format under United States practice.

The present application is believed to be in condition for a full and thorough examination on the merits. An early and favorable consideration of the present application is hereby respectfully requested.

Respectfully submitted,

OBLON, SPIVAK, McCLELLAND,
MAIER & NEUSTADT, P.C.



Gregory J. Maier
Attorney of Record
Registration No. 25,599
Surinder Sachar
Registration No. 34,423



22850

Tel.: (703) 413-3000
Fax: (703) 413-2220
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